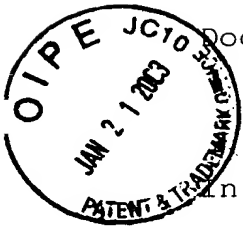


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Socket No. 216-028B

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: KATSIR, D. ET AL.
Serial No. : 09/893,914
Filed : June 28, 2001
For : METHOD FOR PRODUCING HIGH SURFACE
: AREA FOIL ELECTRODES
Art Unit : 1775
Examiner : Stein, Stephen J.

New York, New York 10036
January 17, 2003

Commissioner for Patents
Washington D.C. 20231

AMENDMENT

This Amendment is being filed in response to the
Office Action that was mailed September 17, 2002. Kindly amend
the subject application as follows:

IN THE CLAIMS

Kindly amend ~~claims 29 and 34~~ as follows:

Kindly amend 29 and 34 to read as follows:

BL
29. (Twice Amended) An article of manufacture having a vacuum
deposited fractal surficial structure, which fractal surficial
structure includes both valve metal and an oxide thereof, the
valve metal being selected from the group consisting of
aluminum, titanium, tantalum, niobium, zirconium, silicon,
thorium, cadmium and tungsten.